



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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| Applicant(s): Fumi NABESHIMA et al. | Atty. Docket: PA214WP002 |
| Serial No.: 10/598,933 | Confirmation No.: 2213 |
| Filed: September 14, 2006 | Group Art Unit: 2886 |
| Title: SEMICONDUCTOR WAFER INSPECTION DEVICE AND METHOD | Examiner: Punnoose, Roy M. |

Date: July 6, 2009

Honorable Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450
Mail Stop: Issue Fee


FEE TRANSMITTAL COVER LETTER

Sir:

Enclosed/attached please find a completed PART B – FEE(S) TRANSMITTAL FORM, in duplicate, for the above-described application, in which a NOTICE OF ALLOWANCE AND FEE(S) DUE having a mailing date of April 30, 2009 was received with pleasure.

In addition, as requested by the USPTO at pages 2-3 of its Notice of Allowability dated April 30, 2009, a certified copy of the foreign priority claim document is enclosed herewith to perfect the claim for priority.

Respectfully submitted,


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Application No.: 10/598,933

Atty. Docket No.: PA214WP002

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